



10/28/2000

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant .

Attorney Docket No.

Fuchs et al

PHA 23,578

Application No.: 09/087,141

Art Unit: 2877

Filed: May 28, 1998

Examiner: S. Turner

Title: METHOD AND DEVICE FOR MEASURING THIN FILMS AND SEMICONDUCTOR SUBSTRATES

Commissioner of Patents and Trademarks  
Washington, DC 20231

AMENDMENT

In response to the Office Action dated October 7, 1999,  
please amend the above-identified application as follows:

IN THE CLAIMS:

Please amend Claims 1, 35, 45 and 46 as follows:

1. (Amended) An apparatus for measuring a property of a structure, comprising:

a microchip laser that generates an optical pulse;

a diffractive element that receives the optical pulse and diffracts it to generate at least two excitation pulses;

an optical system that receives at least two optical pulses and spatially and temporally overlaps them on or in the structure to form an excitation pattern that launches an acoustic wave, electronic response, or thermal response that modulates at least a portion of the structure;

a light source that produces a probe beam that reflects off the portion of the structure to generate a signal beam;